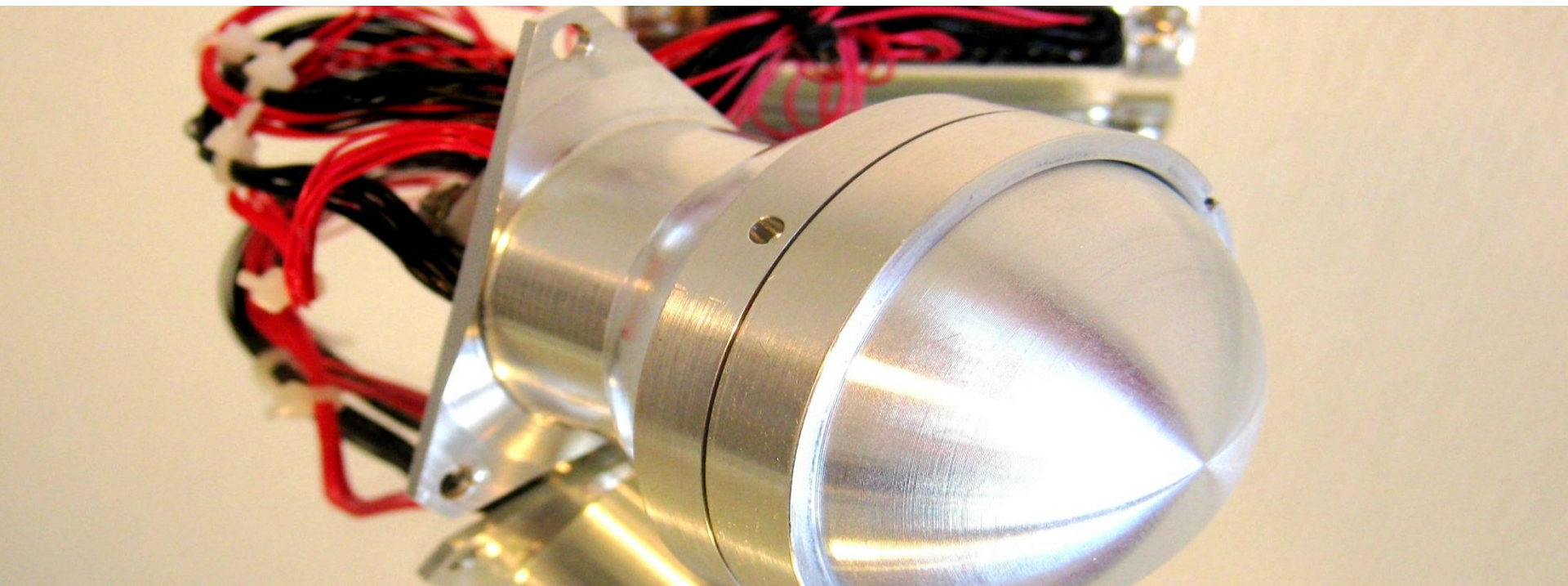


MINIATURIZATION OF COMPONENTS AND SYSTEMS FOR SPACE APPLICATIONS



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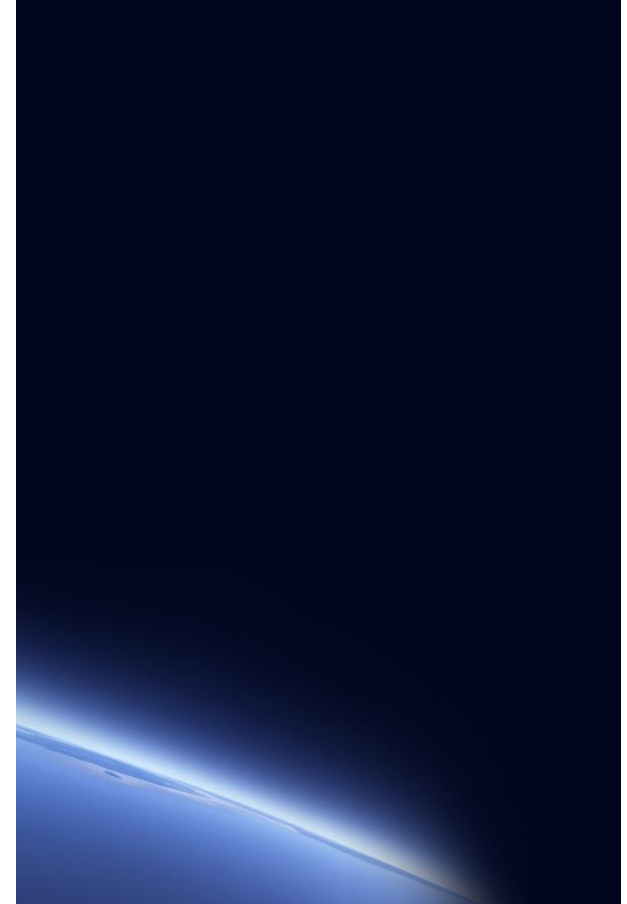


NANOSPACE

READY TO HELP YOU GET MORE FROM SPACE

SSC group of companies

- SSC
- SSC Chile
- SSC Space Australia
- LSE Space
- LSE Space Middle East
- Universal Space Network
- Aurora Technology
- ECAPS
- NanoSpace



GLOBAL PRESENCE



NanoSpace

- a subsidiary to Swedish Space Corporation (SSC)

Background

Spin-off company from Uppsala university.

Founded in 2005.

Located in Uppsala.

Business Idea

NanoSpace provides products and services for the space market based on novel MEMS technology

NanoSpace customer are the system integrators, i.e. the "Prime contractors"

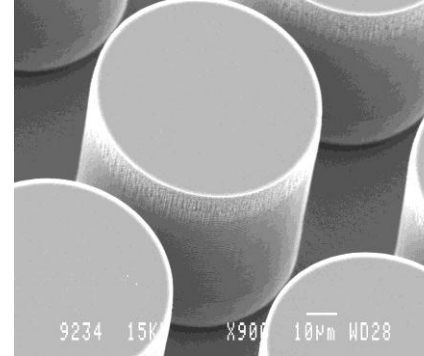
IPR and know-how

NanoSpace has 15 patents (granted or pending)

NanoSpace has its own staff of MEMS R&D engineers and an extensive process database



MEMS Manufacturing Services



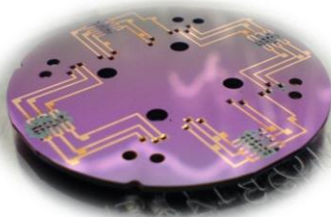
- Access to The Ångström Laboratory with our own staff
- Automatic DRIE equipment owned by NanoSpace
- A huge process database under configuration control

> A number of novel and patented processes

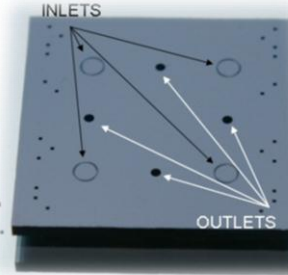
SMÖRGÅSBORD ['smørgøs_bu:d]

Miniaturised MEMS Micropropulsion Components

Thrusters



Flow Control Valves



Filters



Pressure Sensors

Presens (N)



Pressure Relief Valve



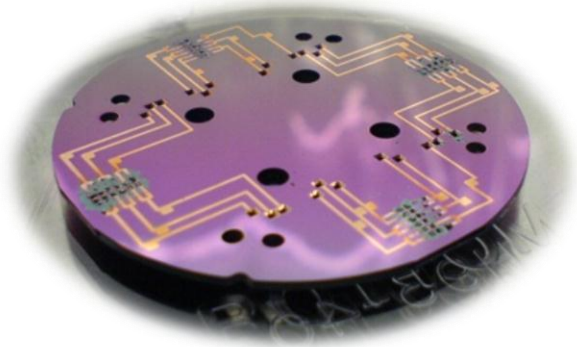
MEMS Isolation Valve



Thruster Pod Assembly – Plenty of MEMS inside



Ø= 44 mm (1.73")
Four thrusters per pod
10 μ N – 1 mN
Mass: 115 g

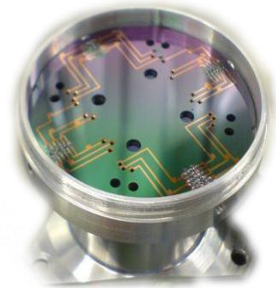


Six-wafer-stack MEMS Thruster Chip

MEMS Micropropulsion Components

- First generation MEMS micropropulsion:

– *Miniaturised, accurate and open-loop*



- Next generation MEMS micropropulsion:

– *Still small, but smarter i.e. Closed-loop control*



Xenon flow control module

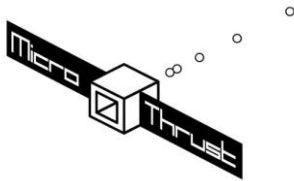


CubeSat propulsion module

Miniaturisation of components in different micropropulsion projects and missions

- Electric micropropulsion:

- *Colloid thruster, pulsed plasma thrusters, electric sail, RF ion thruster (RIT)*



- Chemical micropropulsion

- *Monoprop hydrazine, resistojet, and cold gas*



Motivation

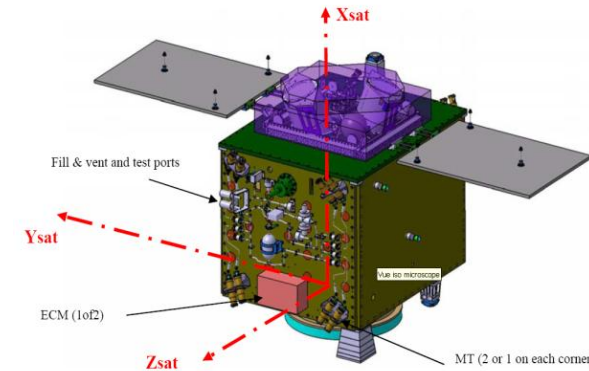
Offer propulsion to enable new missions

- *Advanced Nano- and Cube Sats*
- *Larger spacecraft with stringent requirements*
 - Drag free flights, Orbit change, FF & RV , docking, de-orbit...
 - > *New scientific results*
 - > *Commercial applications*
 - > *Space debris mitigation*

Challenging requirements

Mission thrust requirements given by CNES for MICROSCOPE

Thrust range	1 – 300 μN
Thrust resolution	0.2 μN
Response time	250 ms



MICROSCOPE by CNES

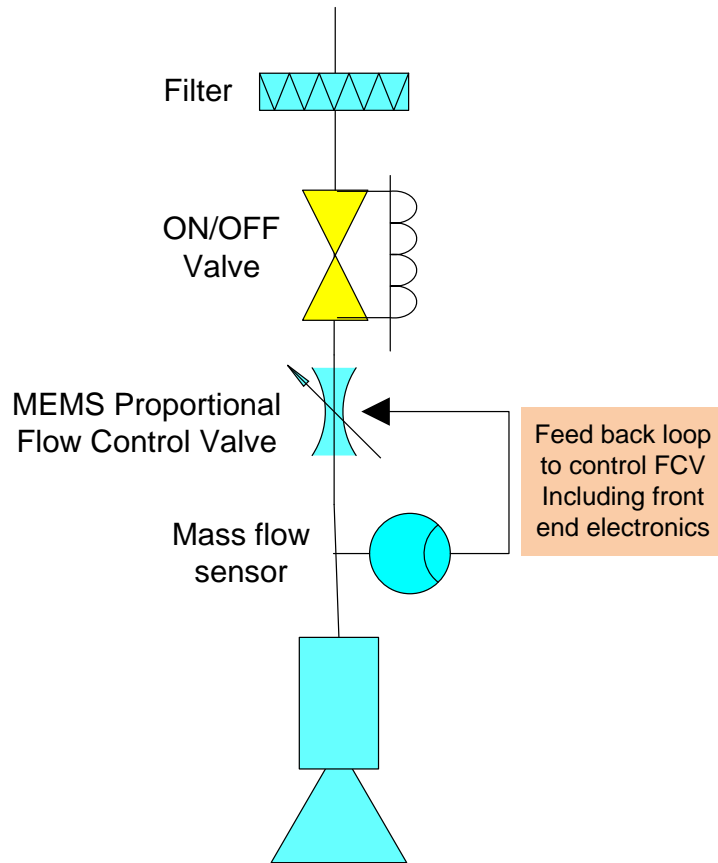
Flow Control Requirements for next generation mini Ion engines

Flow rate range	5 – 50 $\mu\text{g/s}$
Flow rate control accuracy	+/- 5% across the flow range +/- 5% above 25 $\mu\text{g/s}$ and +/- 10% below 25 $\mu\text{g/s}$
Flow rate control resolution	+/- 0.5 $\mu\text{g/s}$



RIT- μX by Astrium

Closed-Loop Flow Control

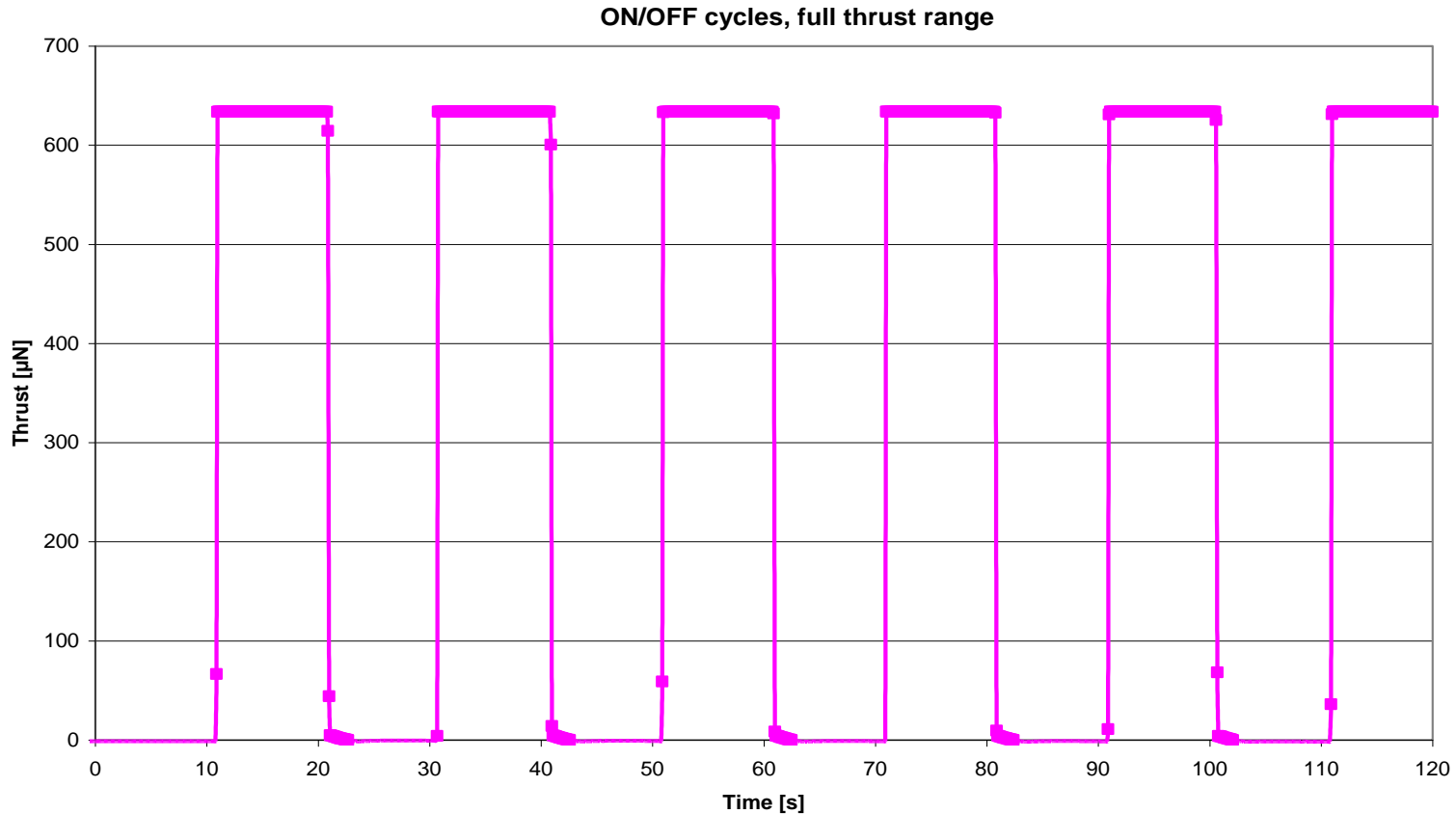


Integrated mass flow sensor provides control signal to the proportional flow control valve

⇒ Closed-loop flow control

Schematic view of a complete closed-loop control thruster.

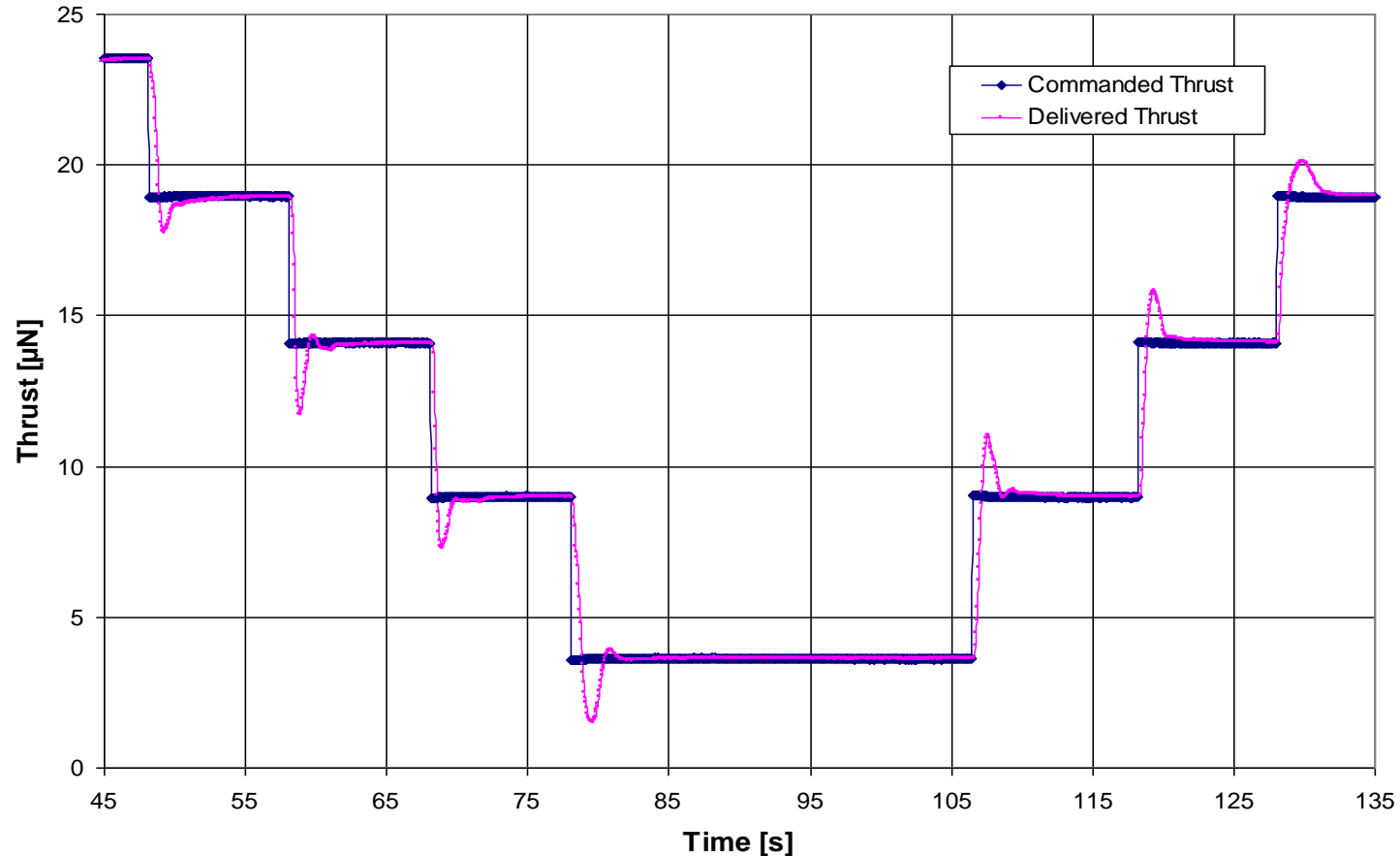
Key capabilities – Like any other



Test result of MEMS thruster operating in ON/OFF mode
(open loop, using solenoid valve only) to show thrust range.
Full thrust can be set in the range **50 micro-Newton** to **5 milli-Newton**

Key capabilities – Unlike any other

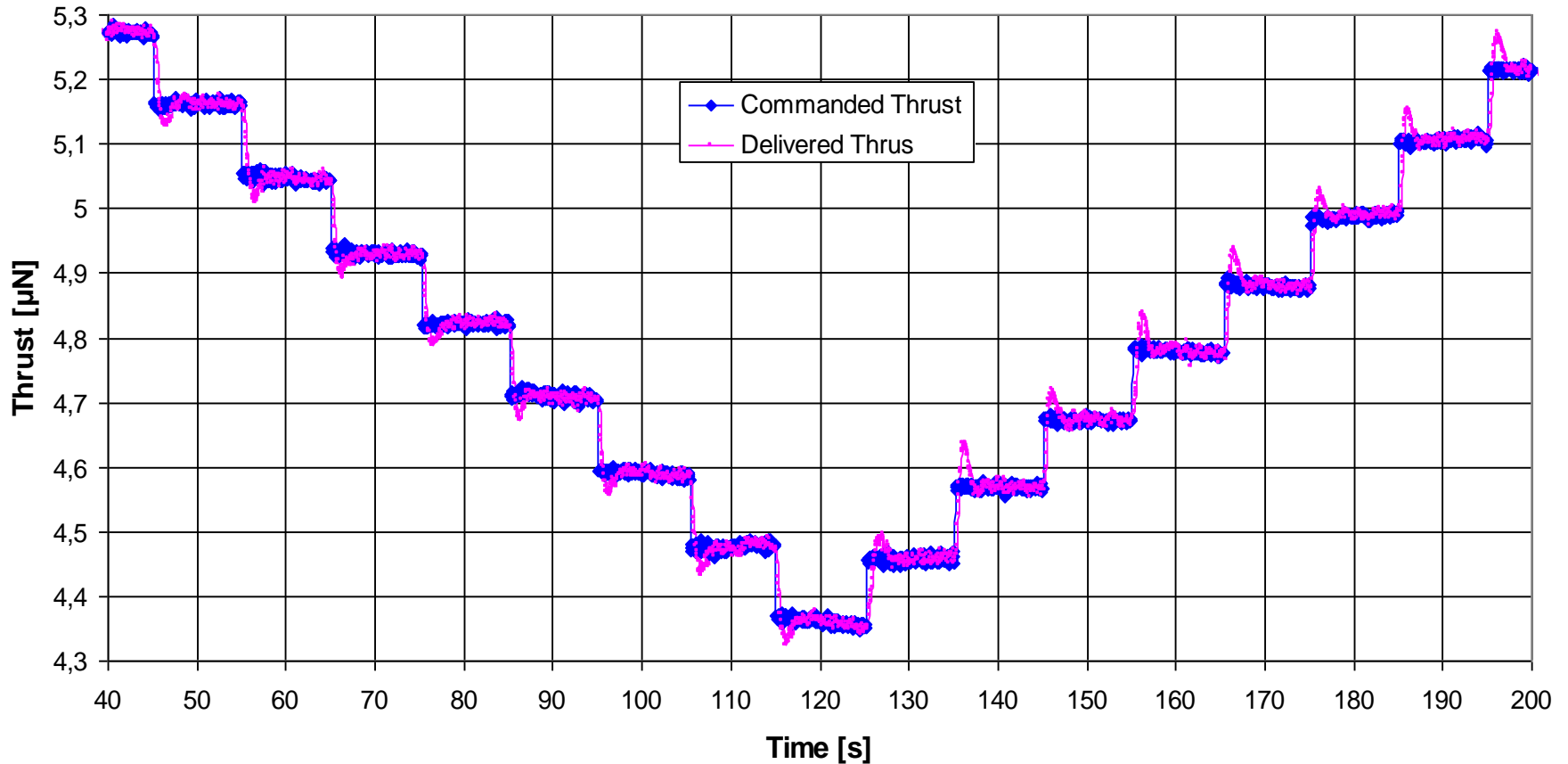
Low thrust regime step response: 5 μ N steps



Test result of a MEMS valve operating in closed-loop control mode showing the thrust response to commanded steps of 5 μ N.

Unique performance

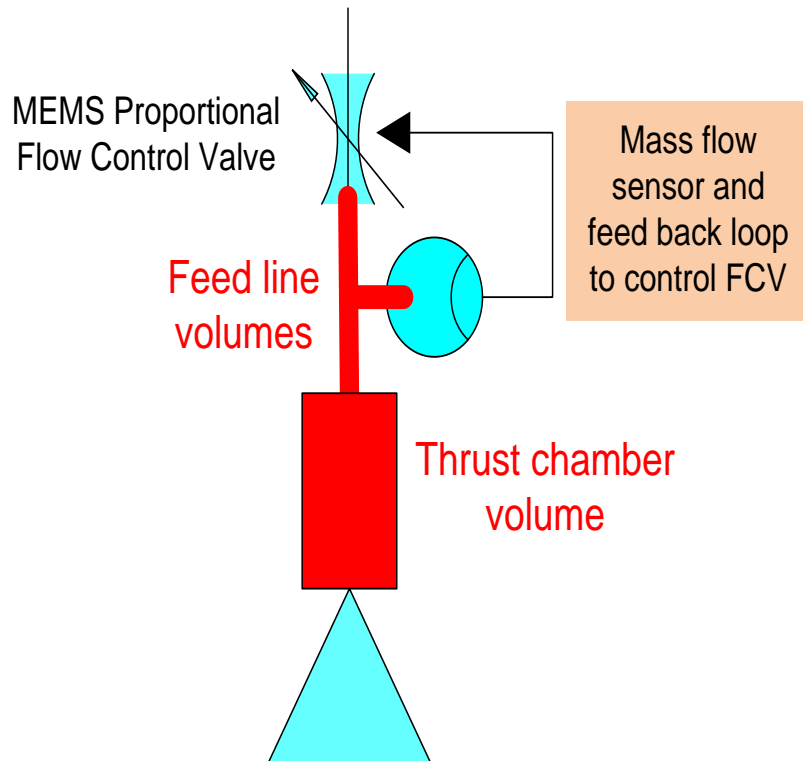
Low thrust regime response: $0.1\mu\text{N}$ steps



Test result of a MEMS valve operating in closed loop control mode responding to the commanded steps of $0.1\mu\text{N}$.

Physics problem

Low flow rates in combination with the wish for fast response



Thruster case:

Requirement: 250 ms in response time

Flow rate: 5 $\mu\text{g/s}$

Response time increases linearly with the internal dead volume

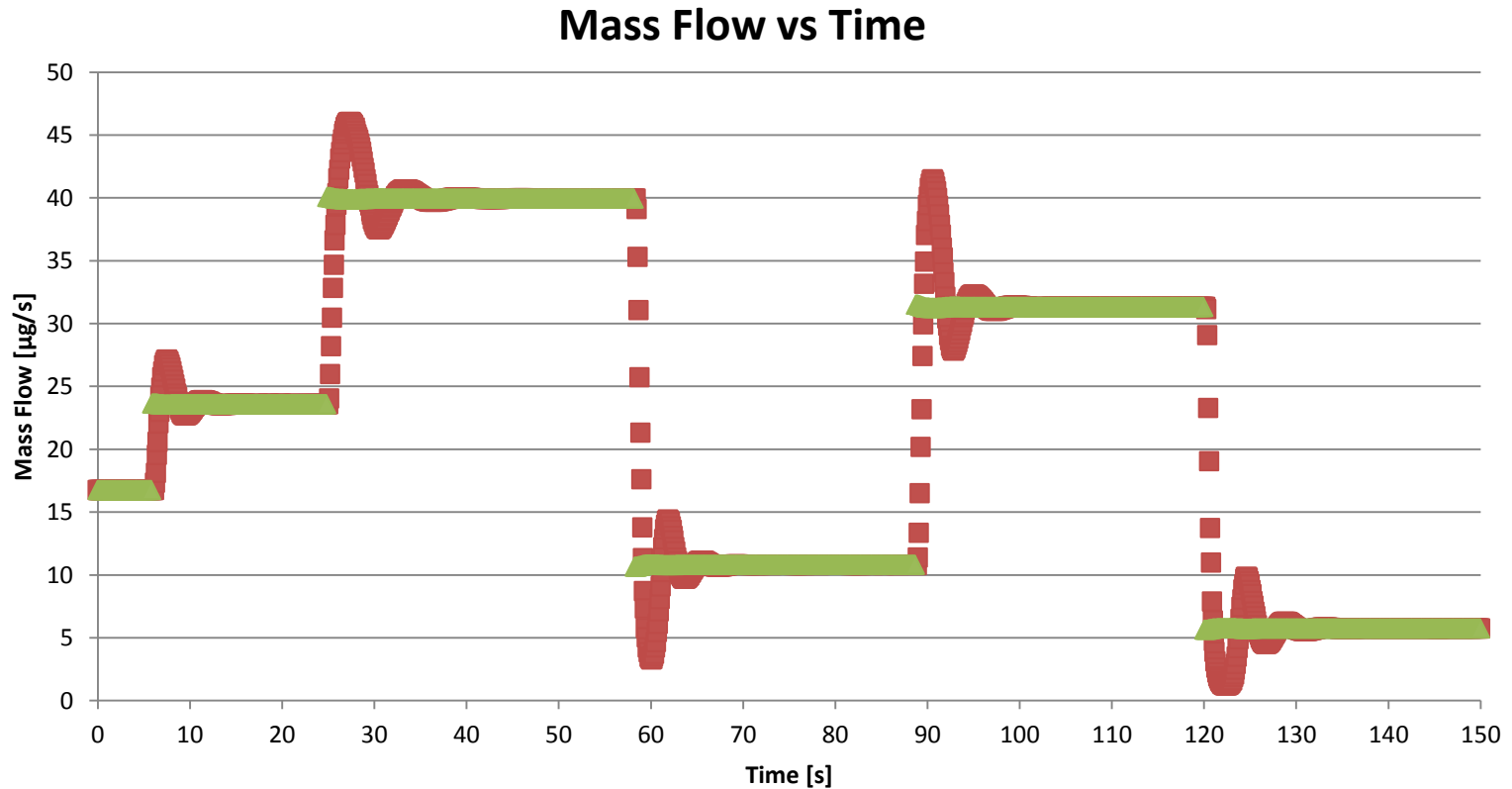
Simplified estimate: $V \sim 10 \text{ mm}^3$

Tubing	Length	Volume
1/8"	5 mm (0.2")	9 mm^3
1/4"	0.62 mm (0.025")	10 mm^3

The Solution - MEMS

In our view, using MEMS technology and integrating the flow control valve, mass flow sensor and chamber/nozzle on a single chip is the best –if not the only- way to realise a closed-loop control thruster that can meet the challenging requirements with low flow rates in combination with fast response.

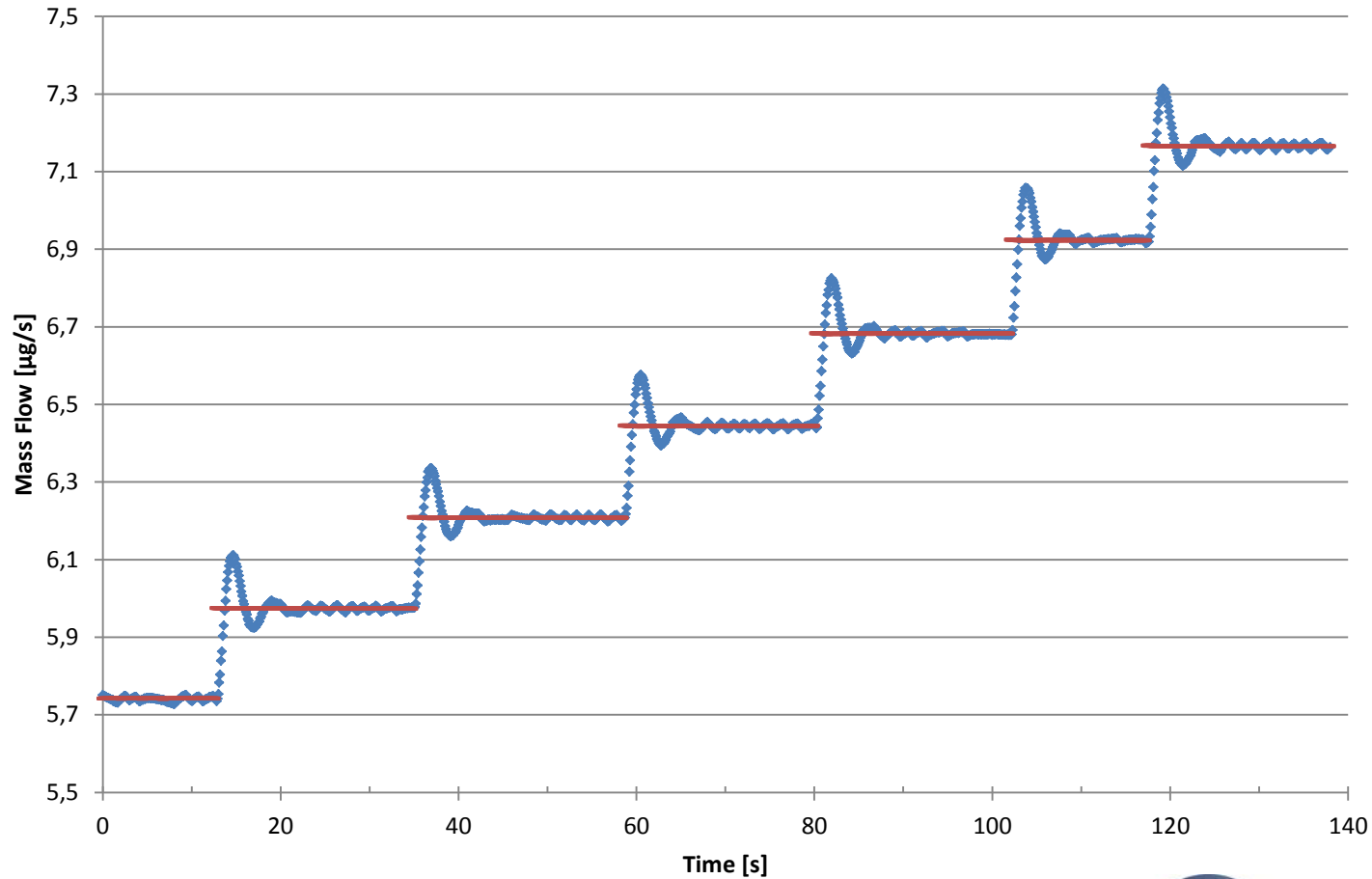
Results – Xenon Flow Control



Capable to operate in full flow regime

Results – Xenon Flow Control

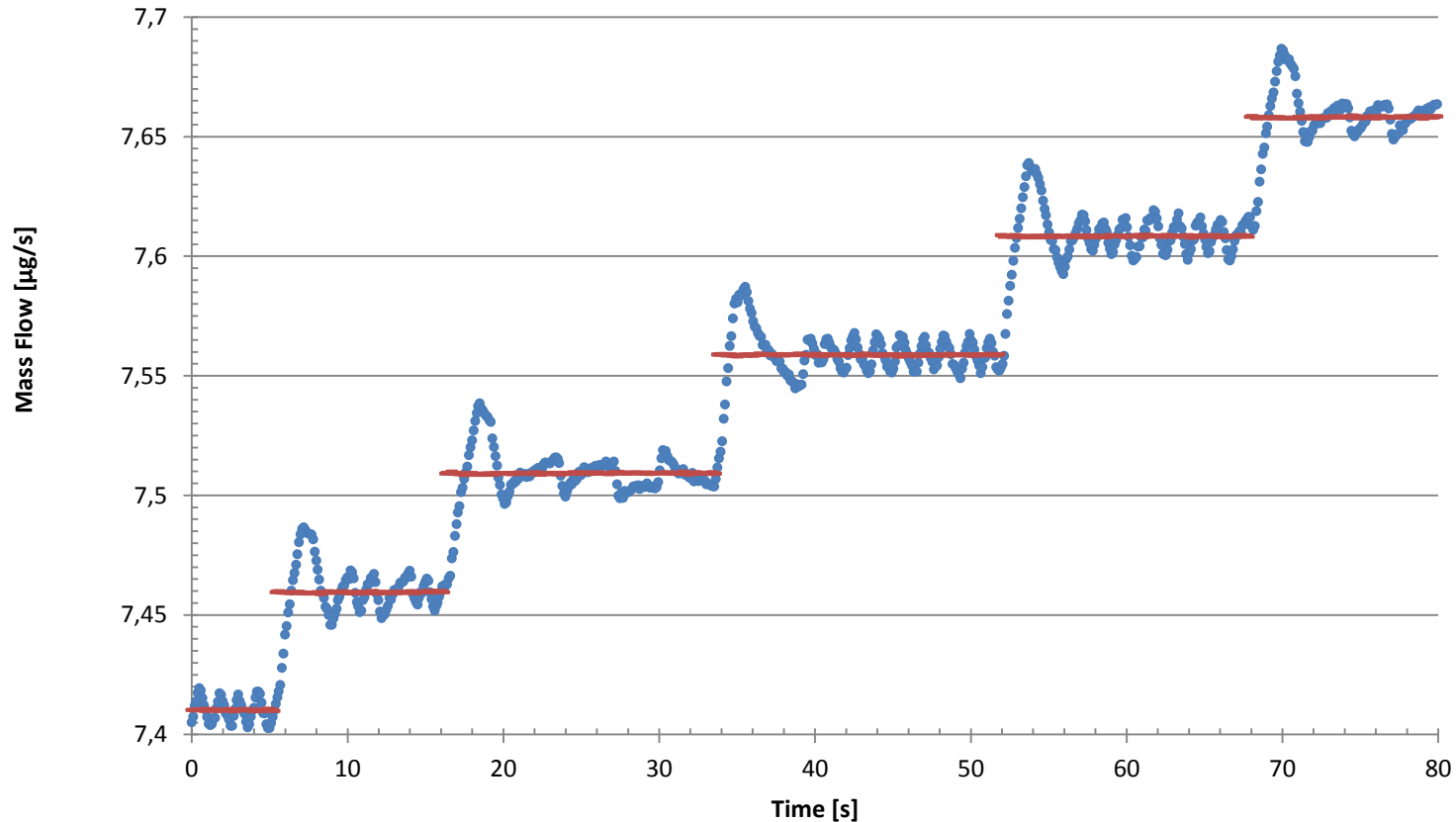
Mass Flow vs Time



Capable to perform minute flow changes

Record shattering resolution

Mass Flow vs Time



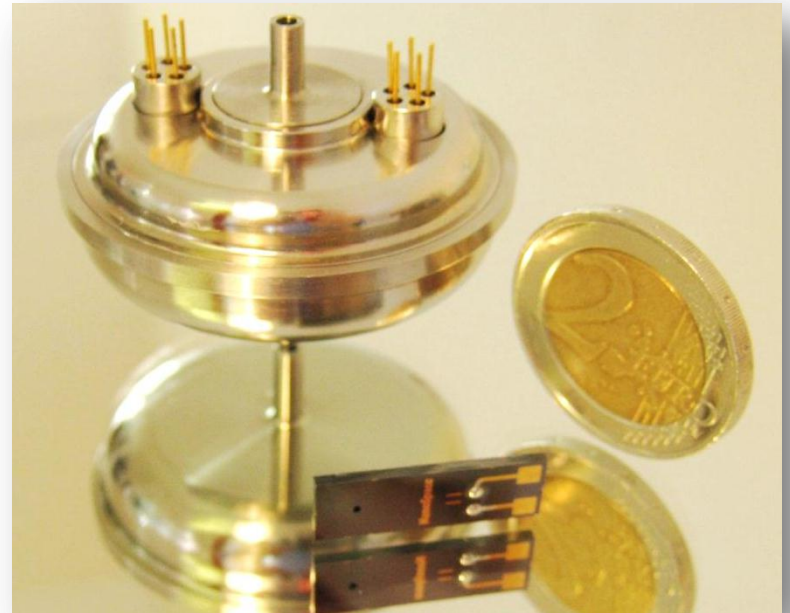
Capable to resolve extremely small changes: 0.2 $\mu\text{g/s}$ (200 ng/s)

Summary – XeFCM H/W

- Designed, manufactured, and tested a Xenon closed-loop flow control module!
- Mass: 63 grams
- Excellent dynamic range
- Step regulation $< 200\text{ng/s}$
- Fast response time

Next step:

- Testing together with mini Ion engine (Astrium's $\mu\text{N-RIT}$ engine)



Summary – Micro Thruster H/W

- Closed-loop thrust control demonstrated with unique performance (in terms of thrust and response time in the low thrust regime)
- Developing a CubeSat propulsion module
 - Four 1mN thrusters with closed-loop thrust control
 - Thrust resolution: $<10\mu\text{N}$
 - Propellant: Butane
 - Total impulse: 40Ns
 - Size: 10*10*3cm
 - Mass: 250g
 - Operating pressure: 2-5 bar
 - Power consumption: 2 W (average, operating)
 - Mechanical interface: CubeSat payload I/F (Pumpkin)
 - Electrical interface: 52 pins analog (0-12V) and digital (SPI)



Next step:

- Finalise the assembly, integration, and testing

MEMS Filters

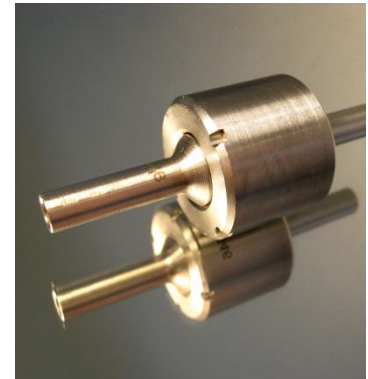
Etched disk technology

- Extreme dimension control
- Zero media migration
- Extreme cleanliness
- High element strength
- High quality coatings
- Compact integration of other components/functions
- Increased redundancy without mass penalty
- Batch processing



Gas Filters

- 5 μ m and 10 μ m filtration rating
- Built-in filters down to 2 μ m absolute filtration

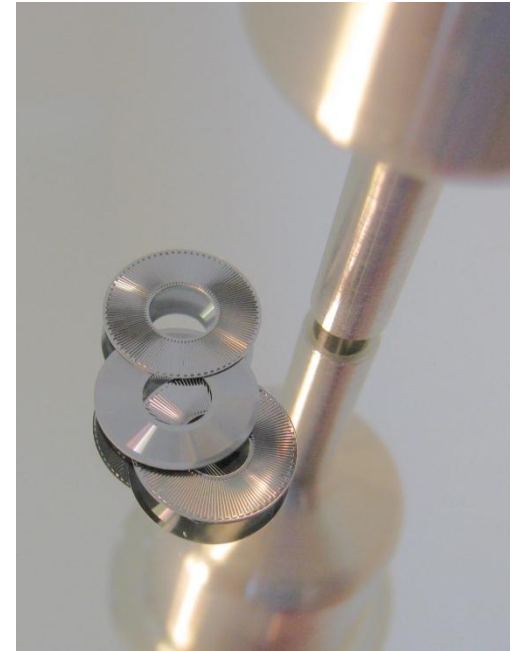


Liquid Filters

- 20 μ m filtration rating

Summary - MEMS Filters

- Etched disk technology
- Both gas and liquid filters
- Built-in filters available
- 2, 5, 10 μm , and 20 μm filtration rating
- Extreme cleanliness and zero media migration
- High capacity filters (high flow rate/low pressure drop)
- Scalable design



Thanks for your attention!

